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Application Number	10/821,010
Filing Date	April 8, 2004
First Named Inventor	Xuming Xiong
Art Unit	1775 1793
Examiner Name	Unassigned
Attorney Docket Number	1014-SP215-US

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
A	Y. Iijima, et al., "In-Plane Aligned YBa ₂ Cu ₃ O _{7-x} Thin Films Deposited on Polycrystalline Metallic Substrates", Appl. Phys. Letters, Vol. 60, pp. 769-771, 1992.		
B	X. Wu, et al., "Properties of YBa ₂ Cu ₃ O _{7-x} Thick Films on Flexible Buffered Metallic Substrates", Appl. Phys. Letters, Vol. 67, No. 16, pp. 2397-2399, 1995.		
C	H. Freyhardt, et al., "YBa ₂ CuO Thick Films on Planar and Curved Technical Substrates", Vol. 7, No. 2, pp. 1426-1431, 1997.		
D	R. Hushne, et al., "Growth of Biaxial Textured MgO-Layers by Ion-Beam Assisted Pulsed Laser Deposition", Crystal Res. Technology, Vol. 35, No. 4, pp. 419-425, 2000.		
E	L. Dong, et al., "Texture Development Mechanisms in Ion Beam Assisted Deposition", Journal of Applied Physics, Vol. 84, No. 9, pp. 5261-5269, 1998.		
F	J. Groves, et al., "Recent Progress in Continuously Processes IBAD MgO Template Meters for HTS Applications, Physica C 382, pp. 43-47, 2002.		
G	ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /K.M.V./		
H			
I			
J			

Examiner Signature	/Kallambella Vijayakumar/	Date Considered	10/01/2008
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¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

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